ISO 23170:2022-06 (E)

Surface chemical analysis - Depth profiling - Non-destructive depth profiling of nanoscale heavy metal oxide thin films on Si substrates with medium energy ion scattering

---

Contents

Page

Foreword iv

Introduction v

1 Scope 1

2 Normative references 1

3 Terms and definitions 1

4 Principle and recommendations of MEIS analysis 1

5 MEIS analysis 2

6 MEIS spectra simulation 2

7 Reporting MEIS analysis results 5

Annex A (informative) Interlaboratory test report 6

Annex B (informative) List of MEIS spectra simulation program sources and a procedure of MEIS spectra simulation using PowerMeis 19

Annex C (informative) Reliability of the IAEA electronic stopping power data 22

Annex D (informative) Fitting parameters A, B, C, D from the IAEA database 24

Bibliography 29